Bio:

Dr. Bill Cardoso

Bill Cardoso, Ph.D., is the Chief Executive Officer and founder of Creative Electron. A native of Brazil, Bill came to the US in 1998 as a 'guest engineer' at the US Department of Energy's renowned Fermi National Accelerator Laboratory (Fermilab), one of the leading research institutions for high energy and nuclear physics. In a nine year career at Fermilab and starting with an associate electronics degree earned in Brazil at age 13, Bill took on significant project, personnel, and budget responsibilities while at the same time earning MS and PhD degrees from the Illinois Institute of Technology (IIT) and an MBA from the University of Chicago.

After leaving Fermilab as Department Head for Electronic Systems Engineering, Bill moved to California to become the VP of Technology at the government contracting firm he eventually acquired from the estate of the founder to create Creative Electron in 2008.

An industry thought leader, Bill has been recognized as IIT's 2011 Outstanding Young Alumnus Awardee for his contributions to science and technology. He is also a Senior member of the Institute of Electrical and Electronics Engineers (IEEE), Surface Mount Technology Association (SMTA), American Physics Society (APS), and the International Society for Optics and Photonics (SPIE).

Bill is a holder of several patents in the areas of radiation detection, radiography, and quality inspection.

Bill is an active member of his community and is part of the technical committee of several conferences including the SMTA/CALCE Component Counterfeit Conference, SMTA International, Components for Military and Space Electronics Conference, SPIE Photonics, and the IEEE Nuclear Science Symposium.

Bill serves in the G19 committee writing the standards for counterfeit detection for the aerospace and defense markets. He is also a reviewer of academic proposals for the Department of Energy, Department of Homeland Security, and National Science Foundation. He is the author of over 120 technical publications, a contributor to 2 books, and is a frequent speaker at technical conferences on radiography and optical inspection worldwide.